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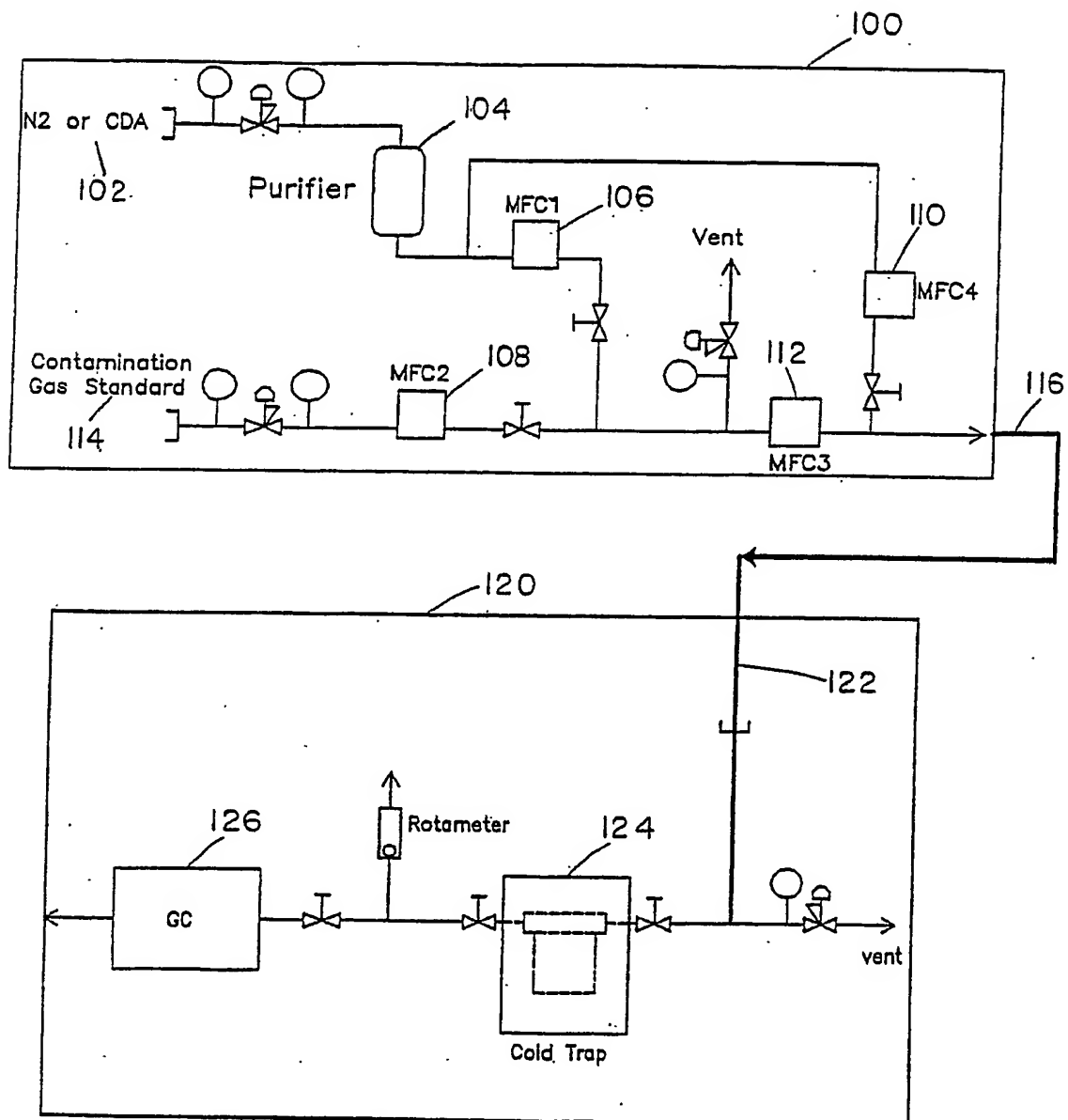


FIG. 1 PRIOR ART

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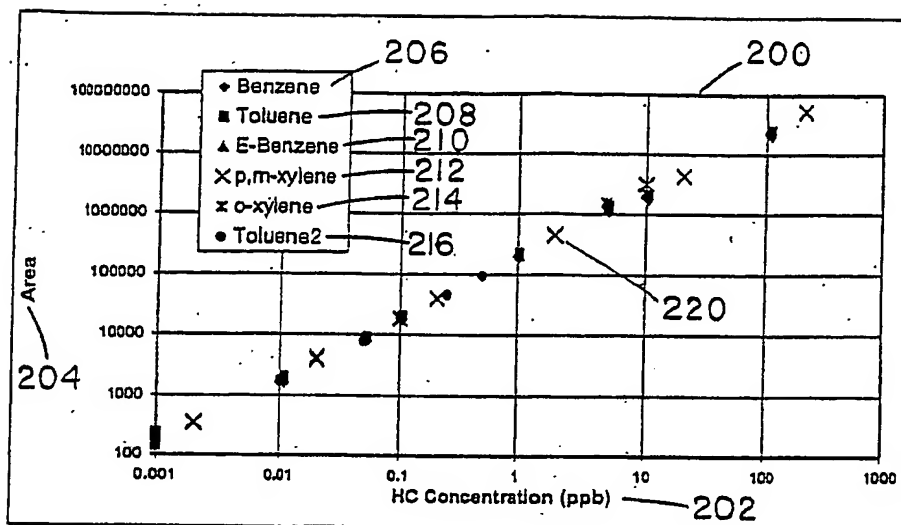


FIG. 2 PRIOR ART

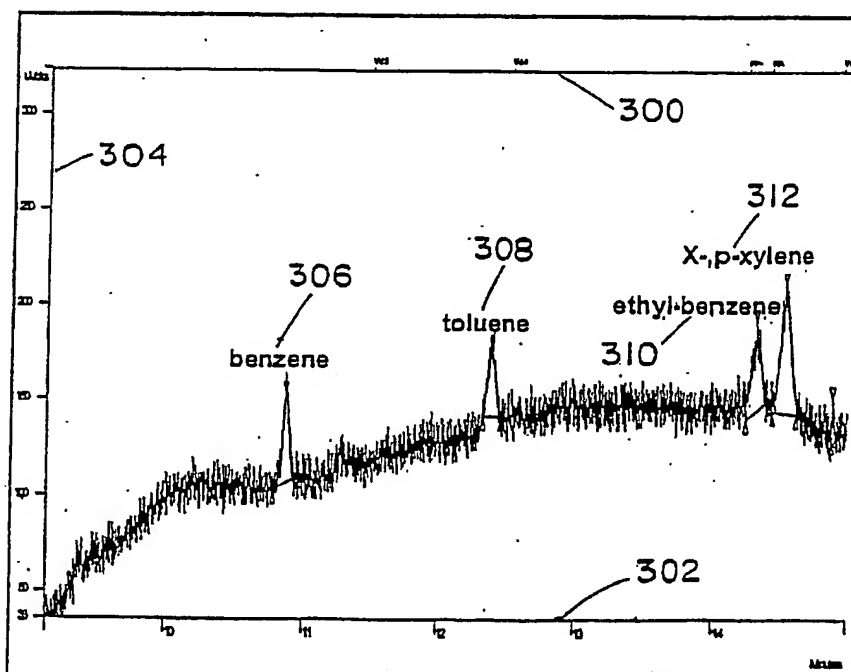


FIG. 3 PRIOR ART

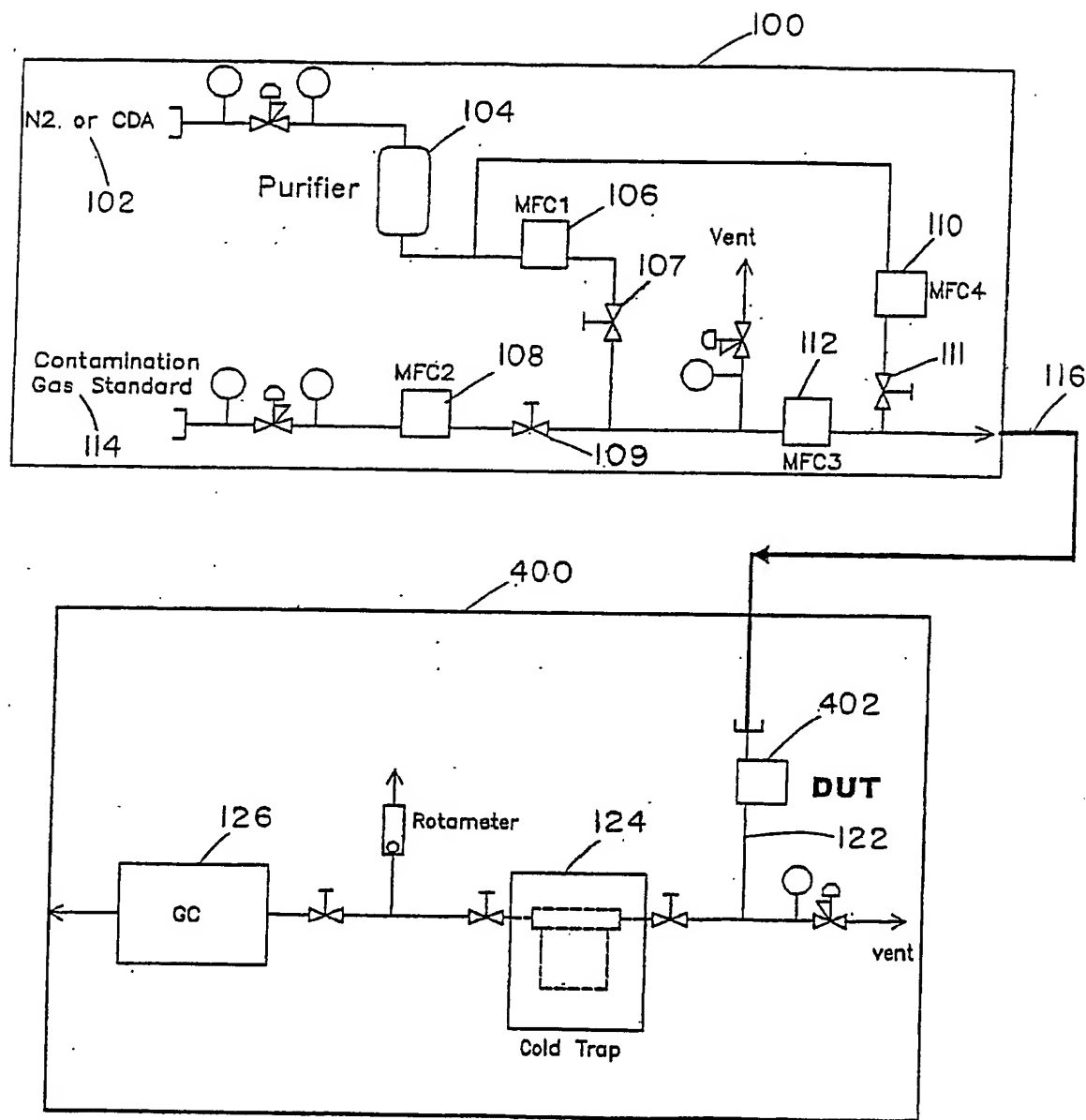
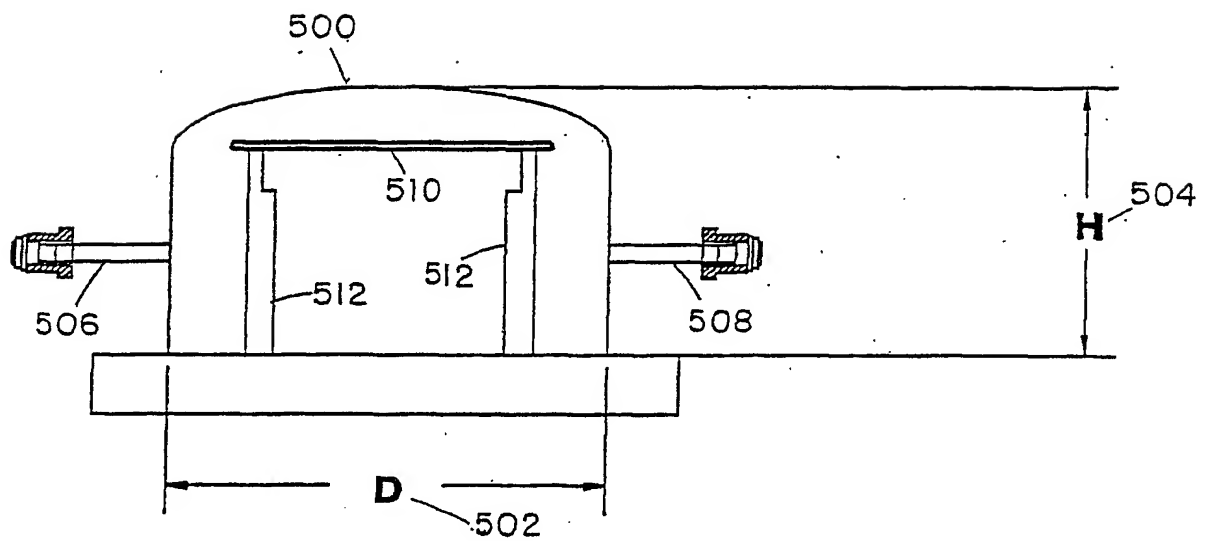


FIG. 4

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Wafer Chamber

FIG. 5

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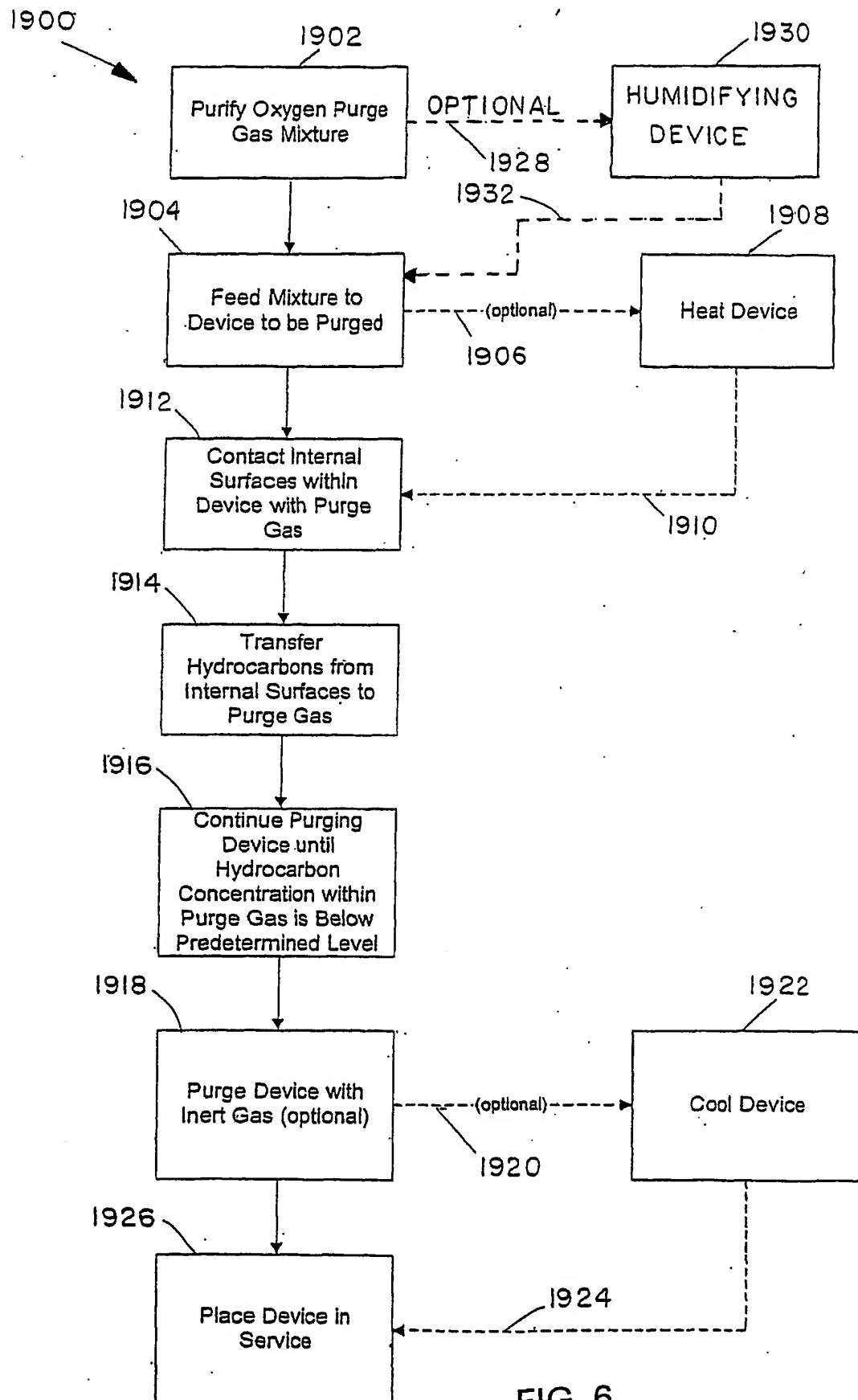


FIG. 6

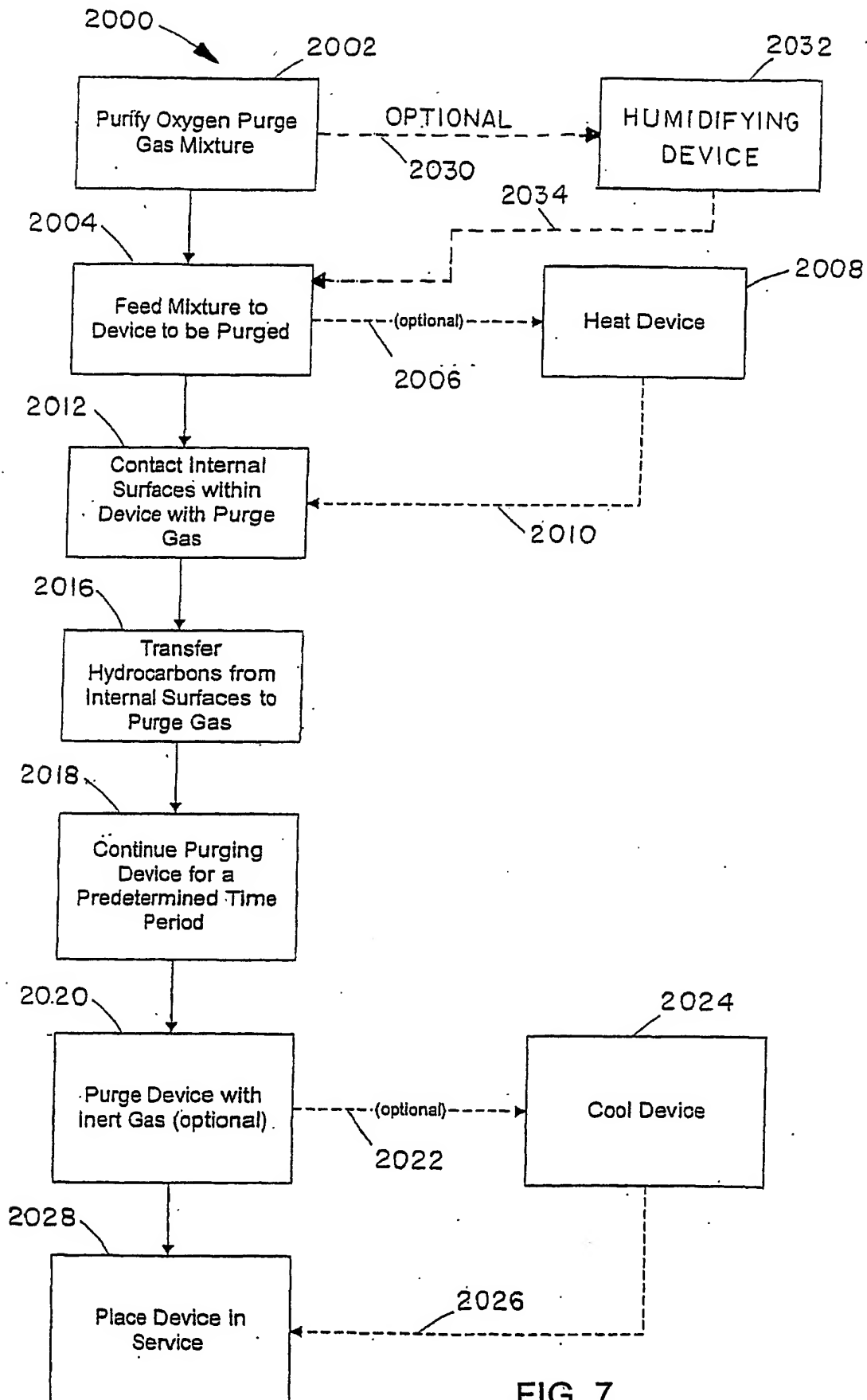
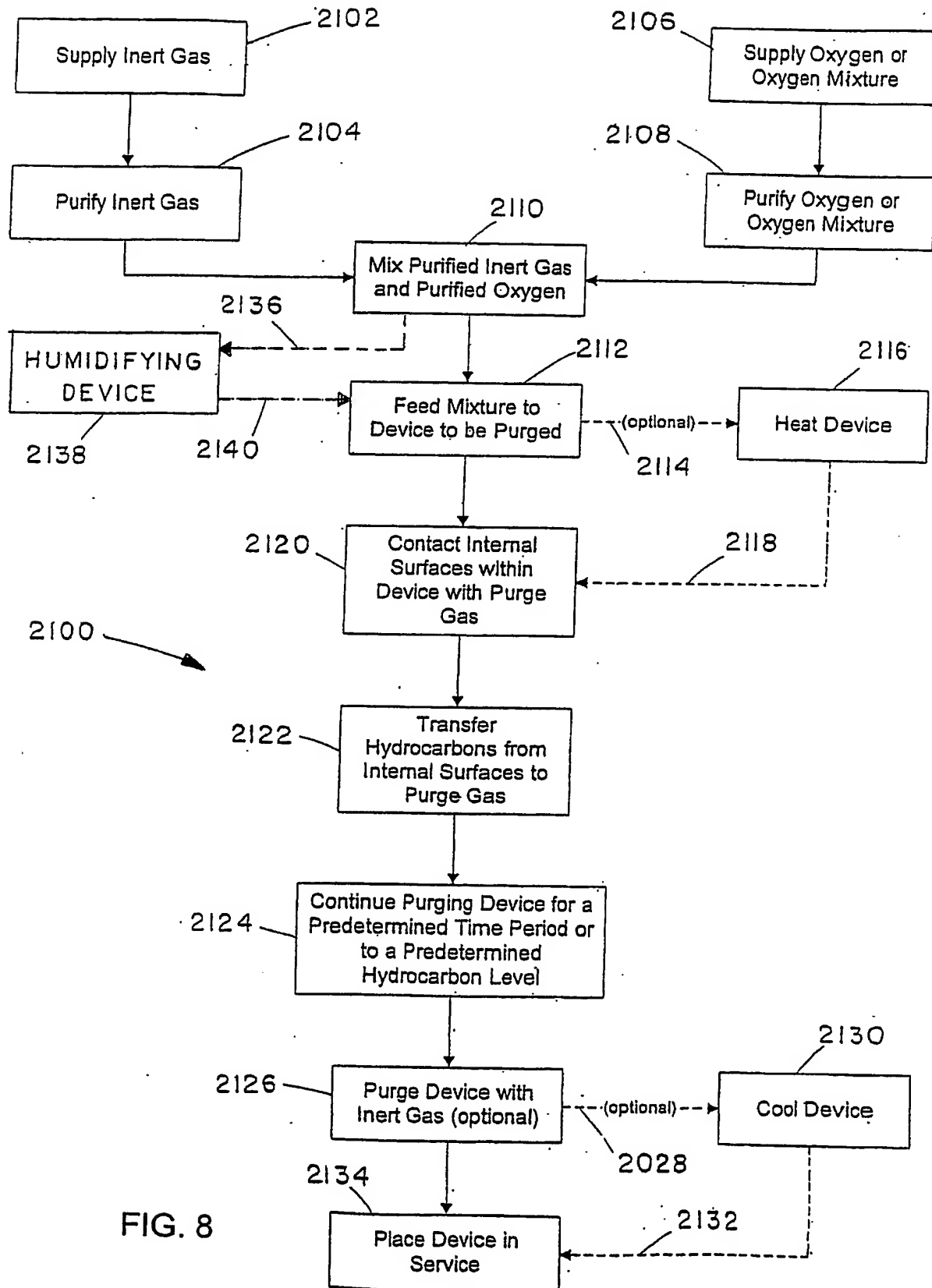


FIG. 7

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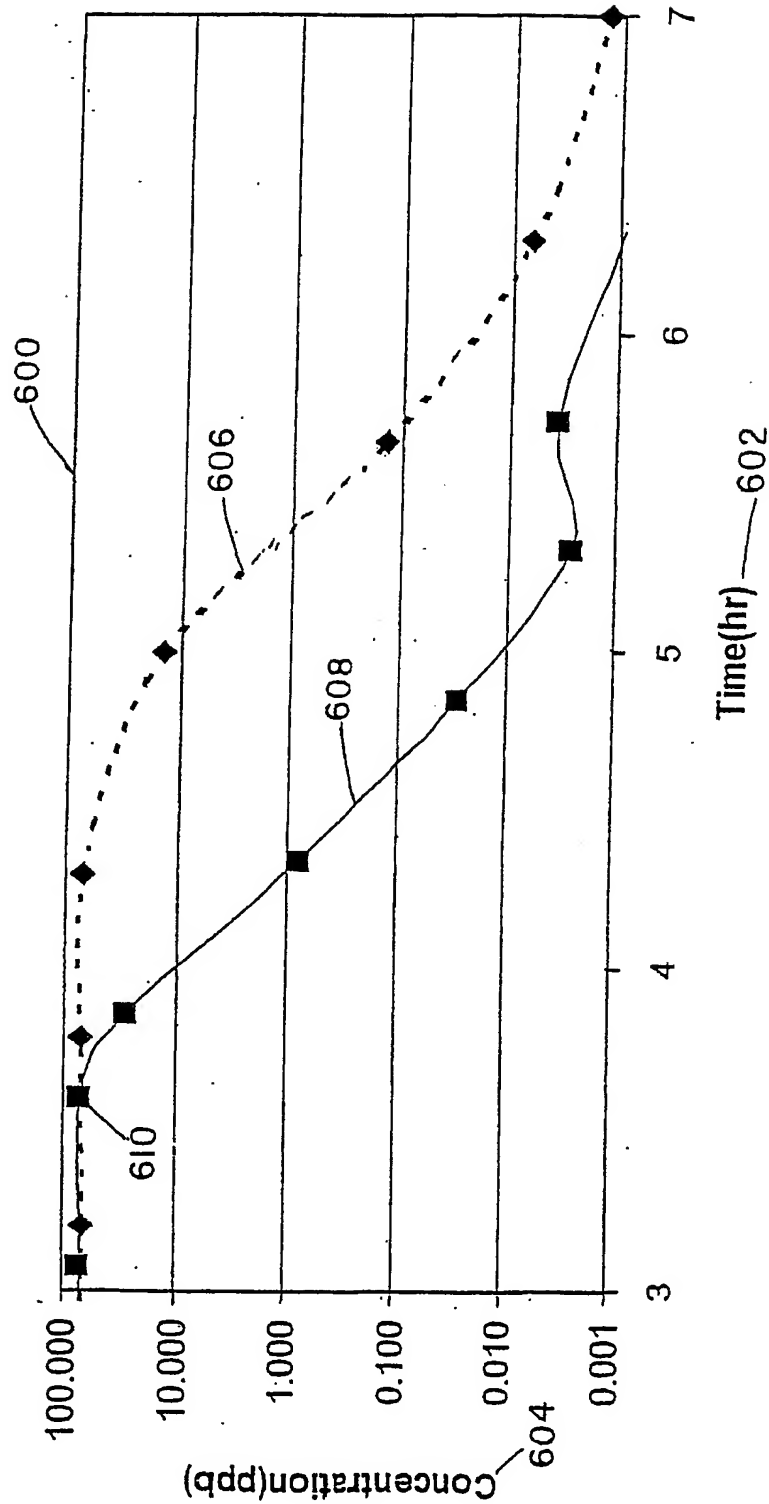


FIG. 9



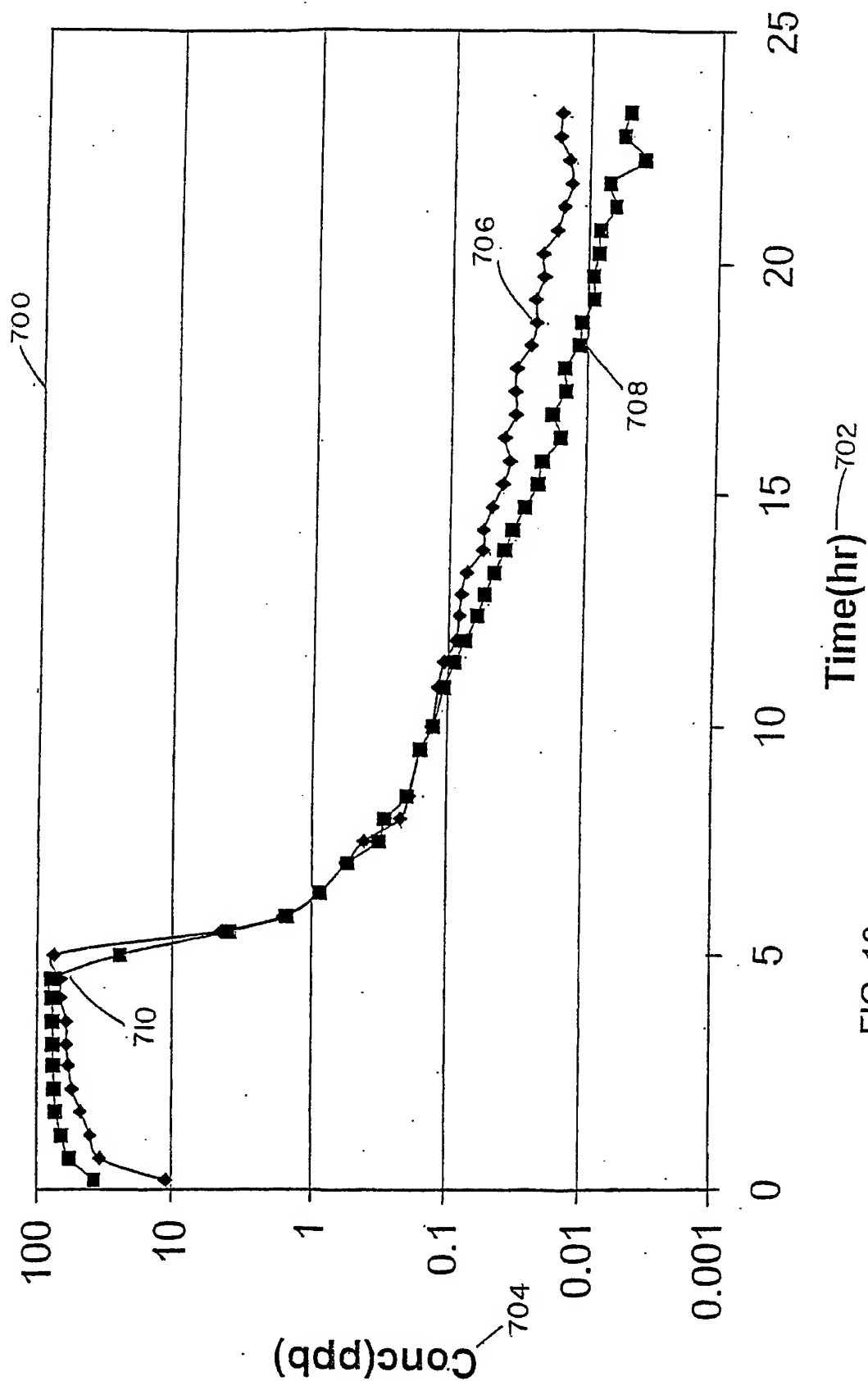


FIG. 10

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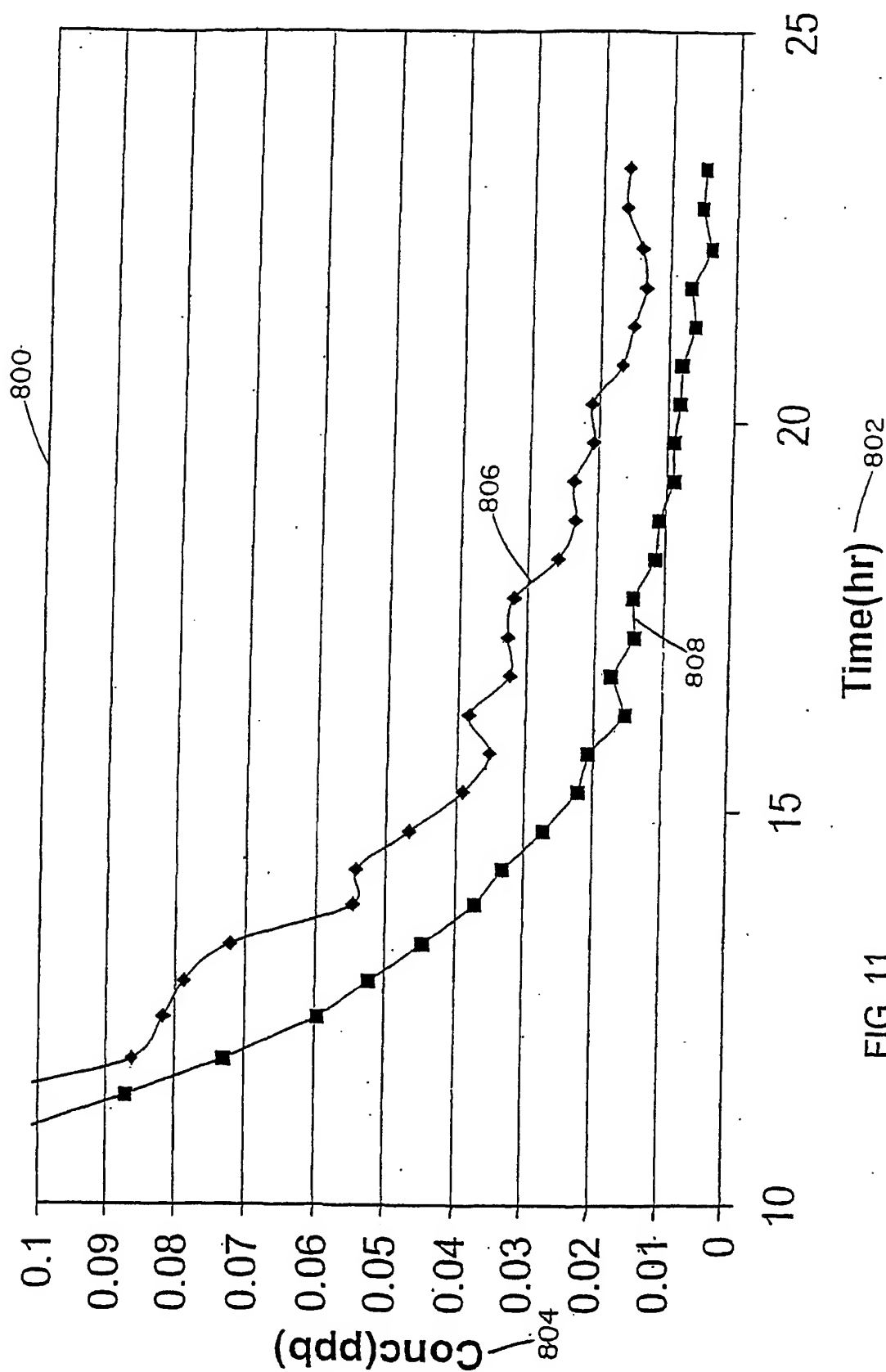


FIG. 11

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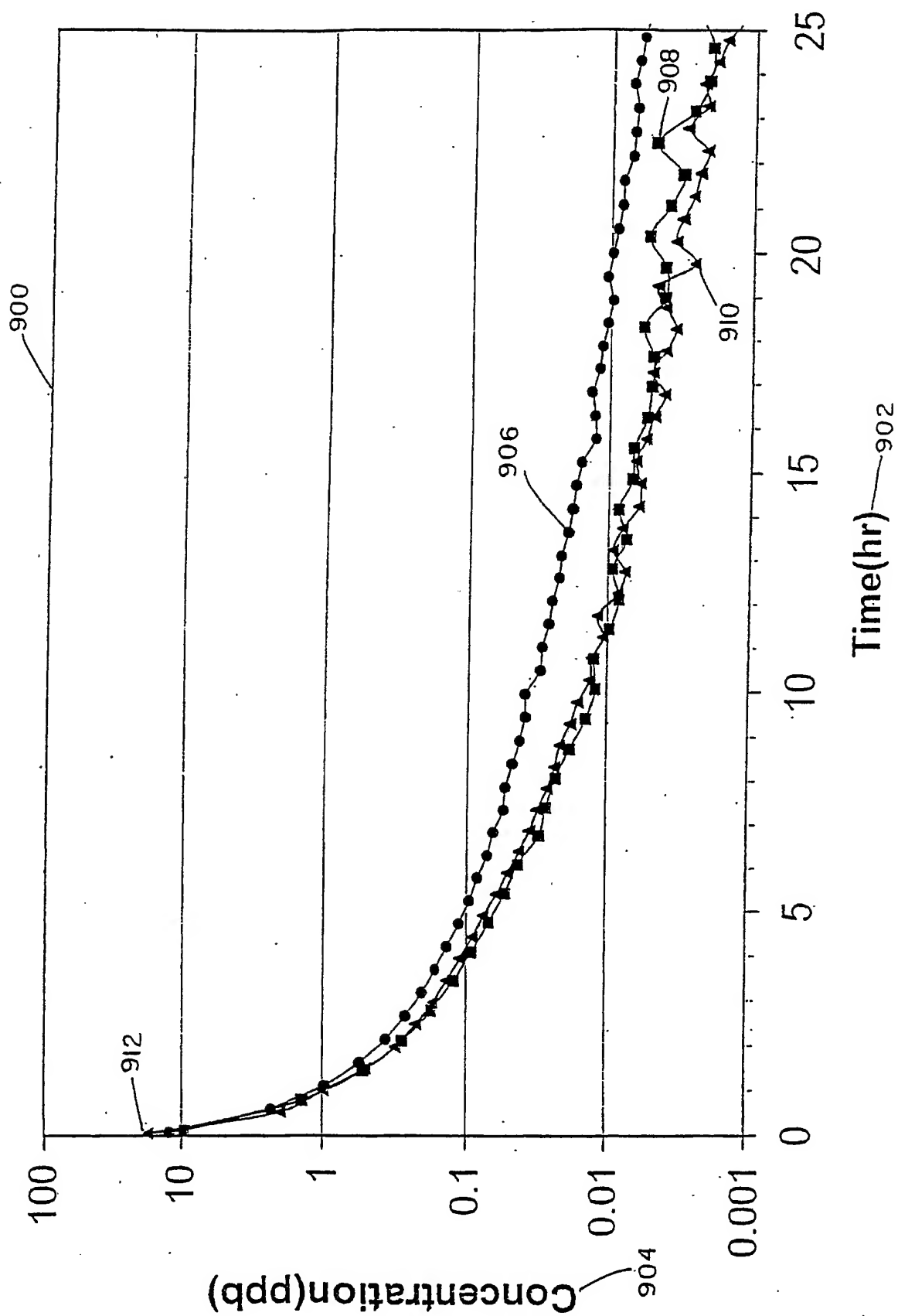


FIG. 12

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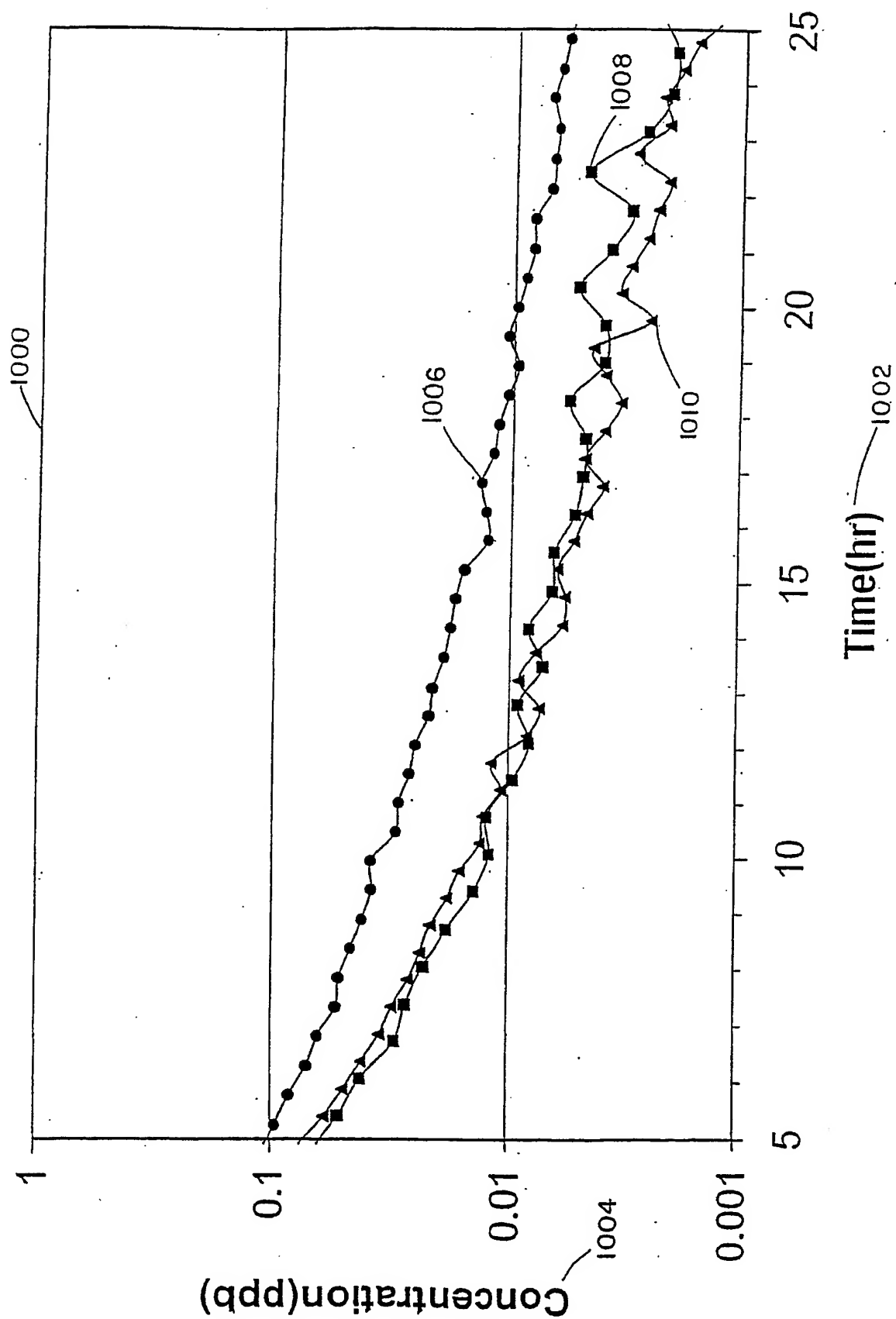


FIG. 13

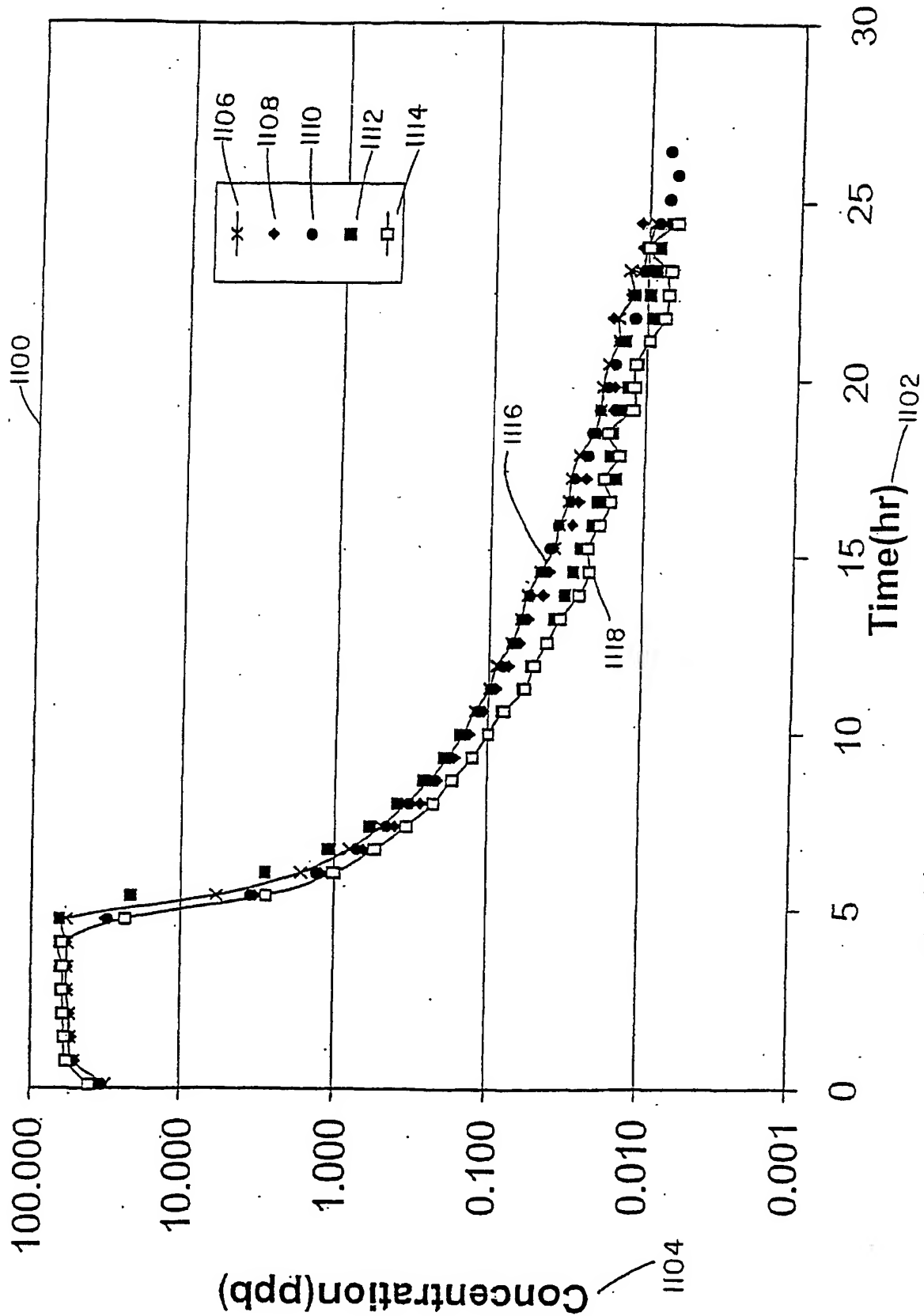


FIG. 14

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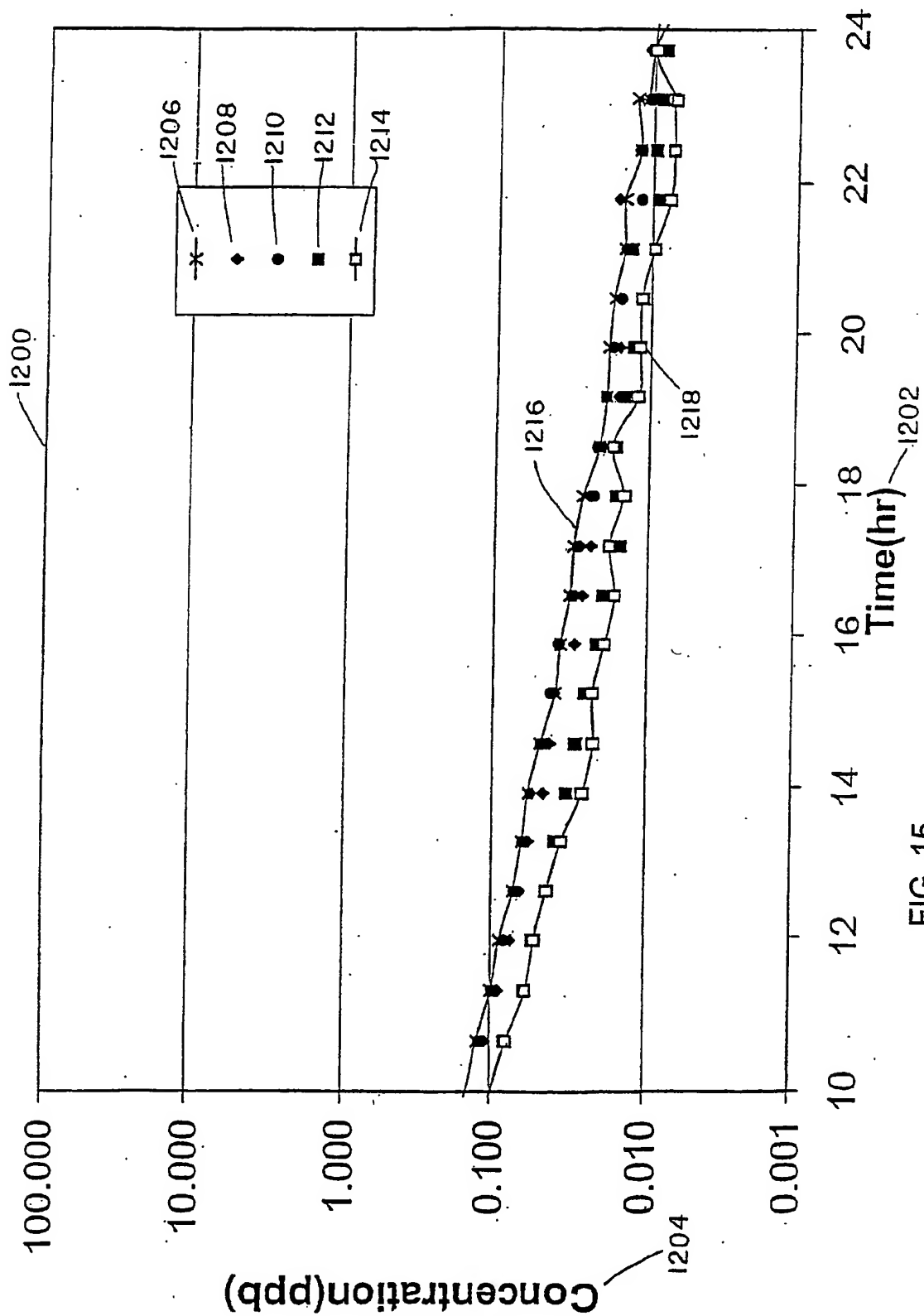


FIG. 15

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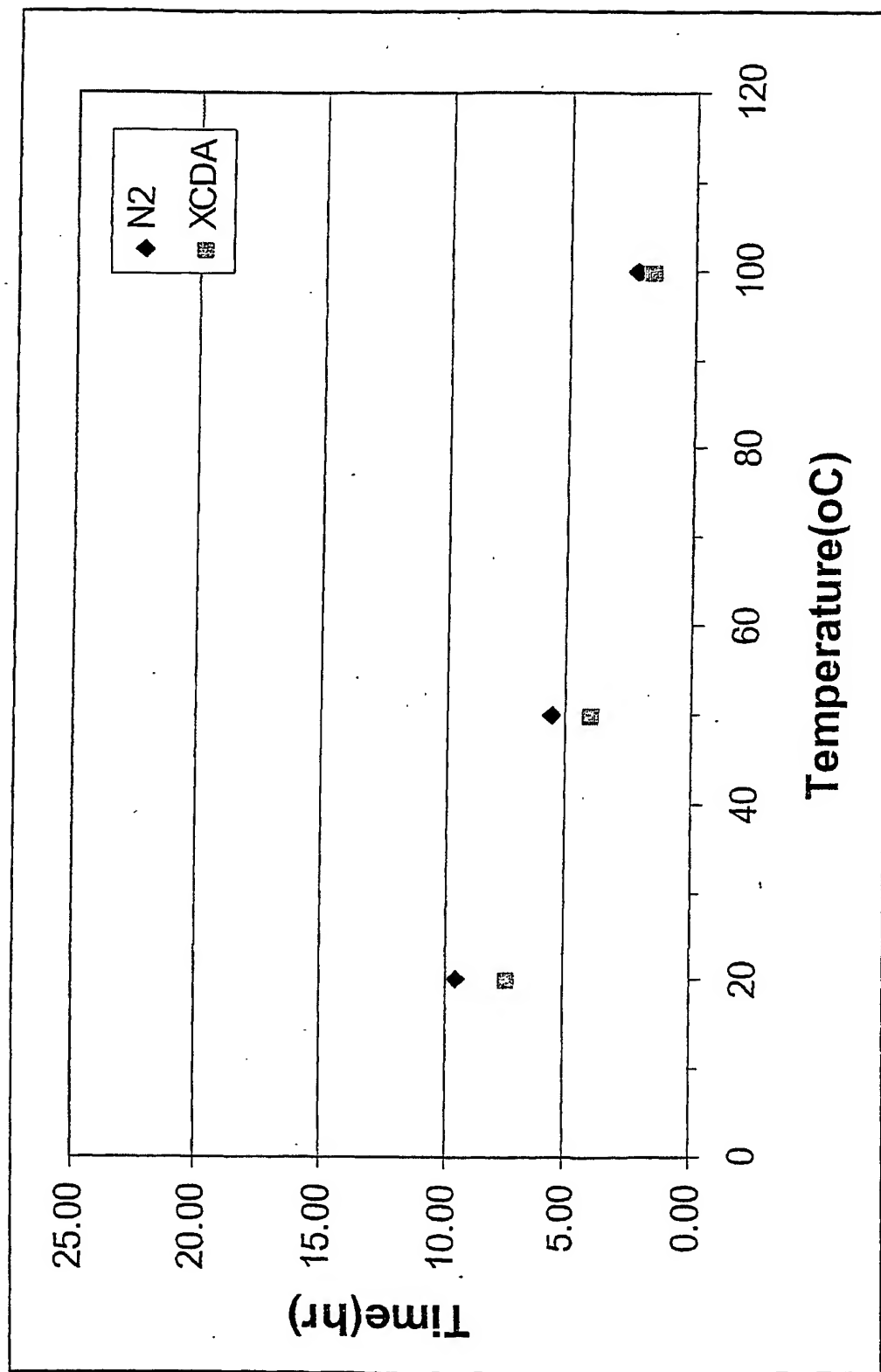


FIG. 16

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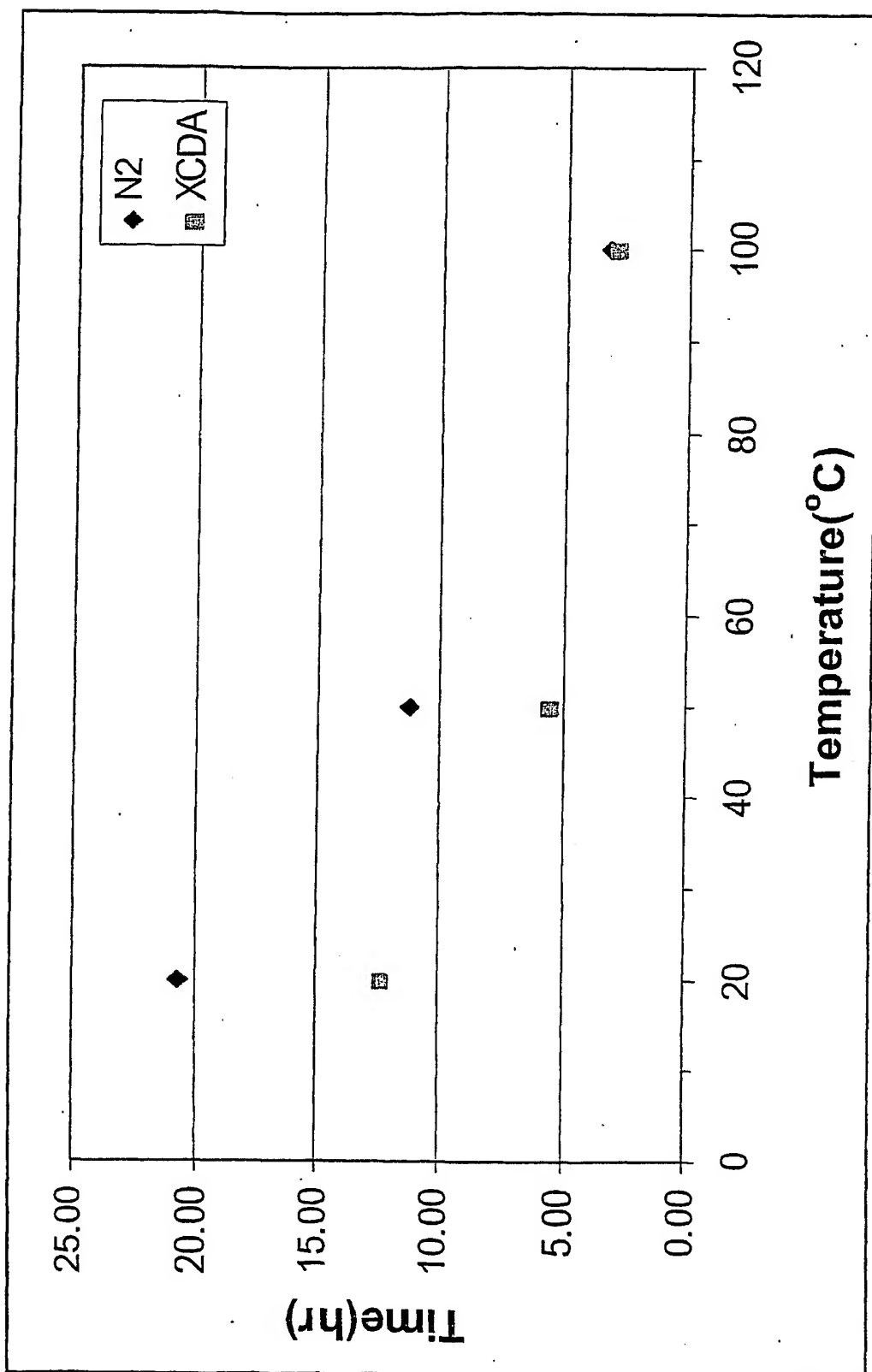


FIG. 17



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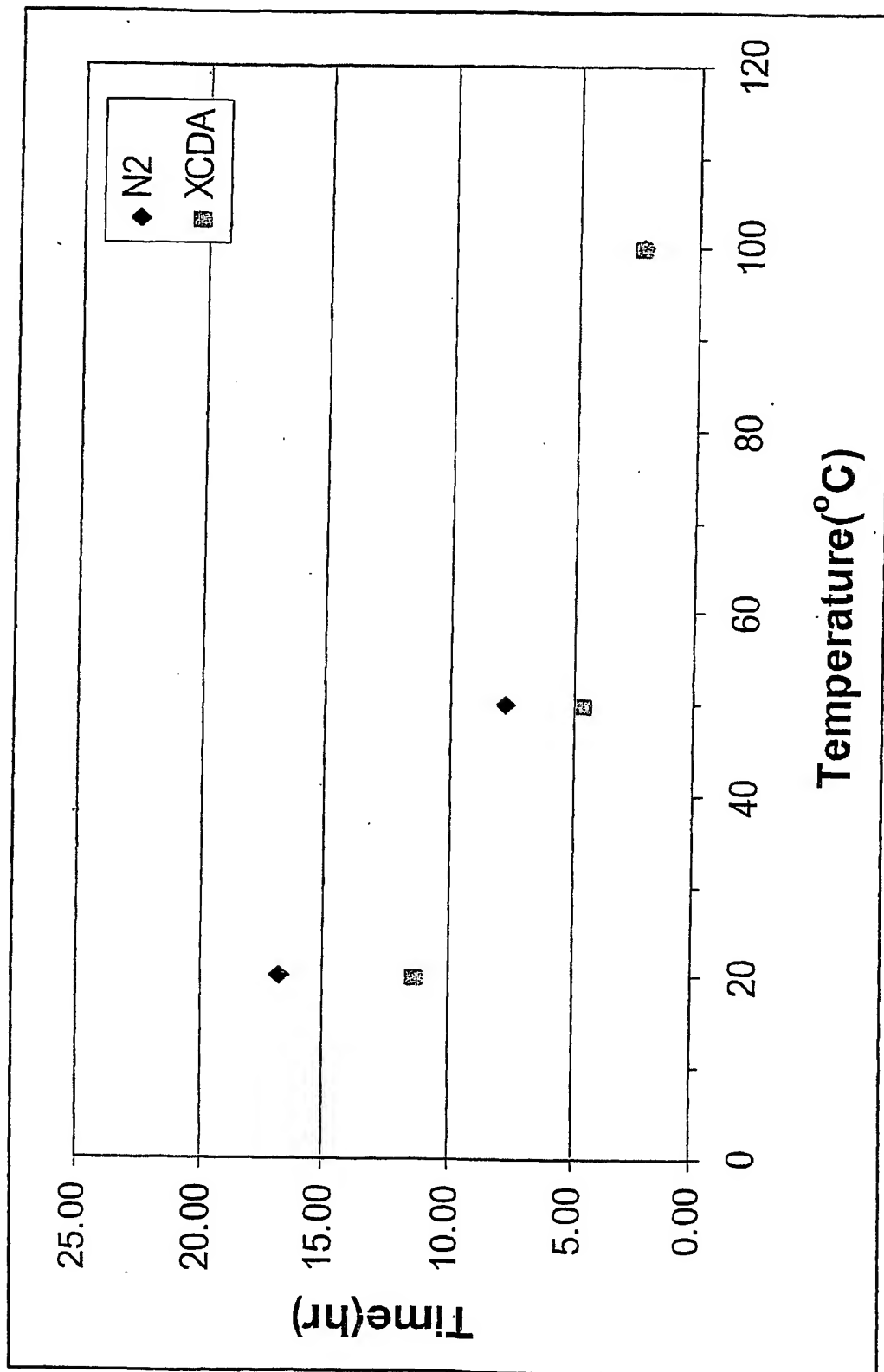


FIG. 18

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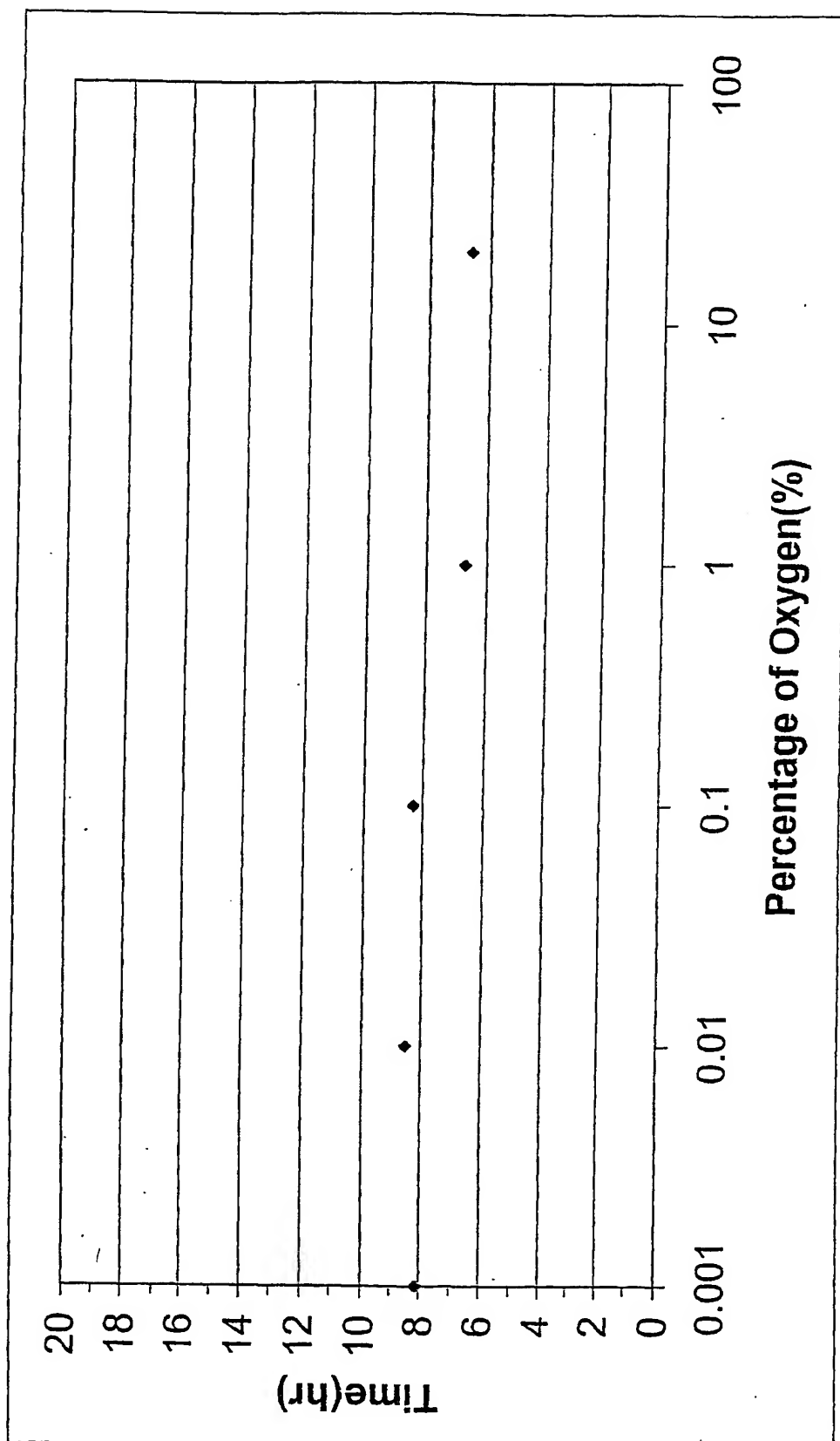


FIG. 19

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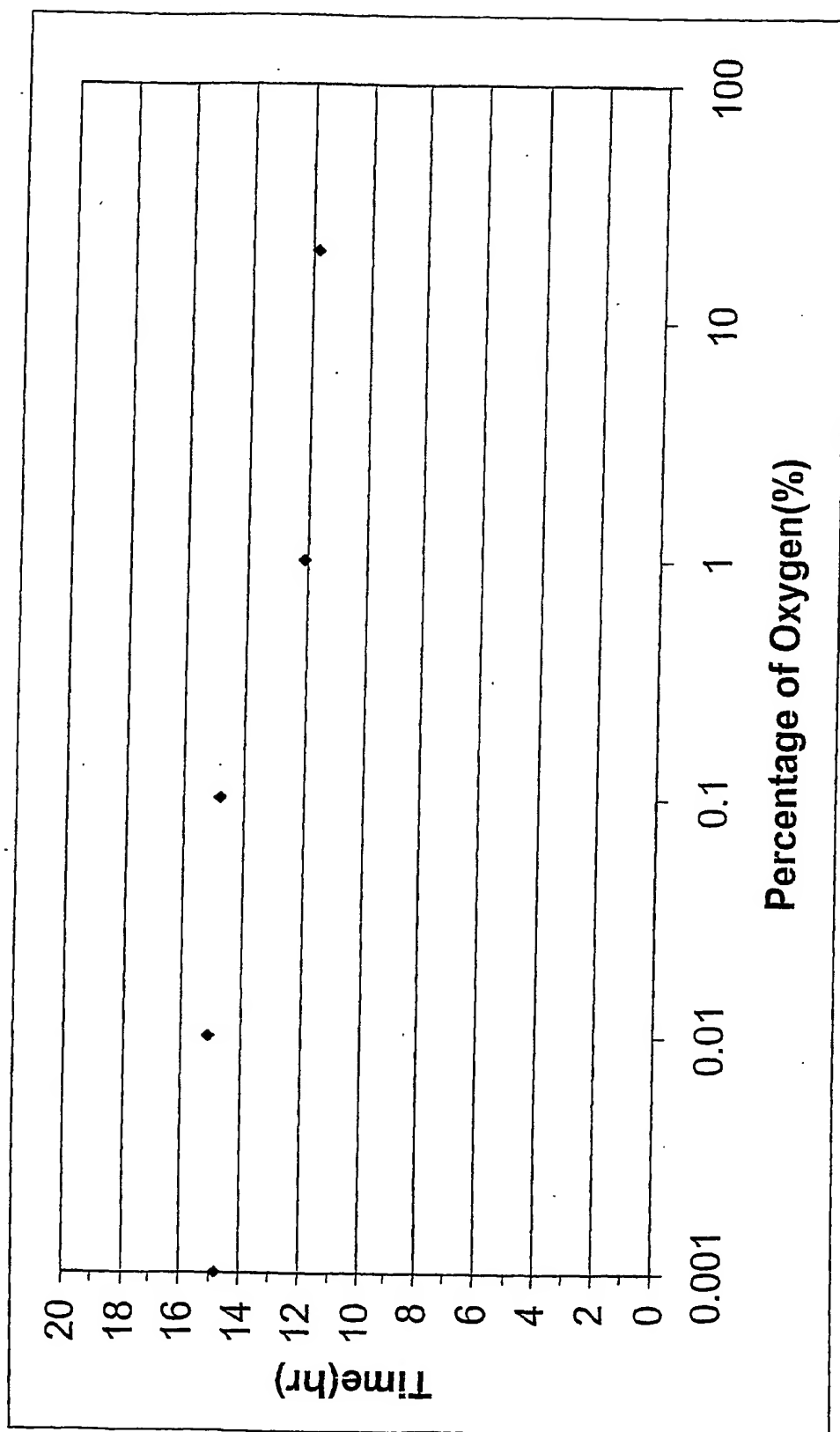


FIG. 20

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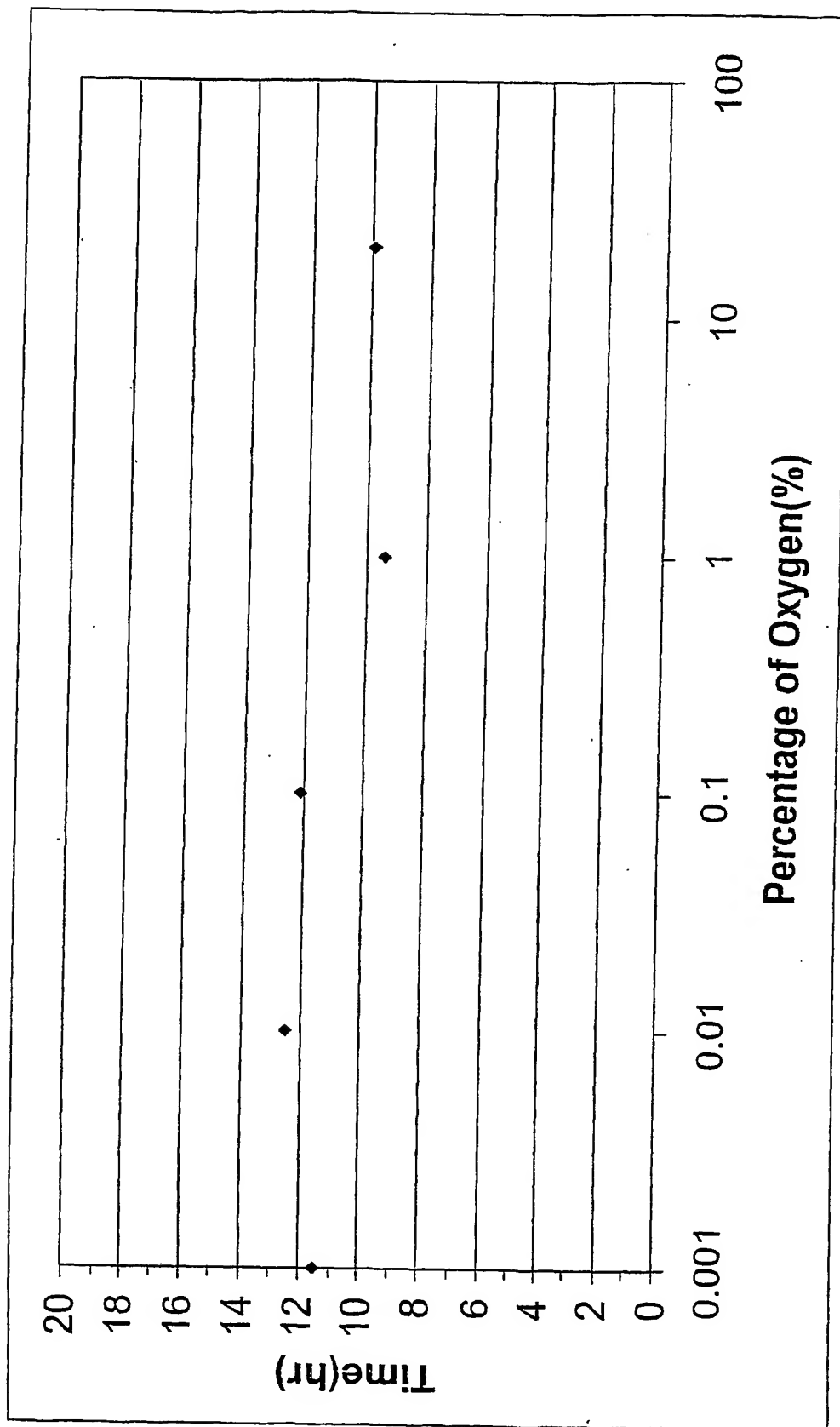


FIG. 21

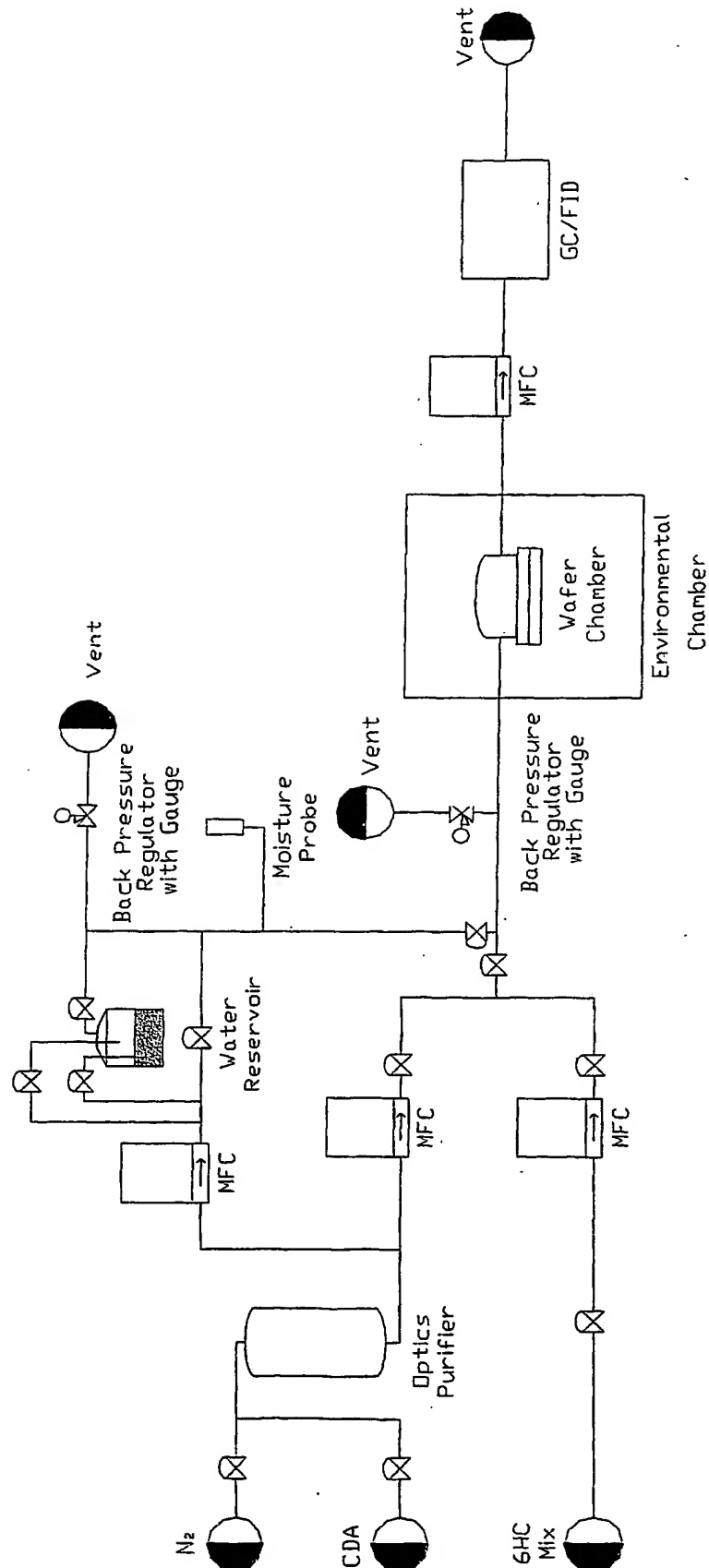
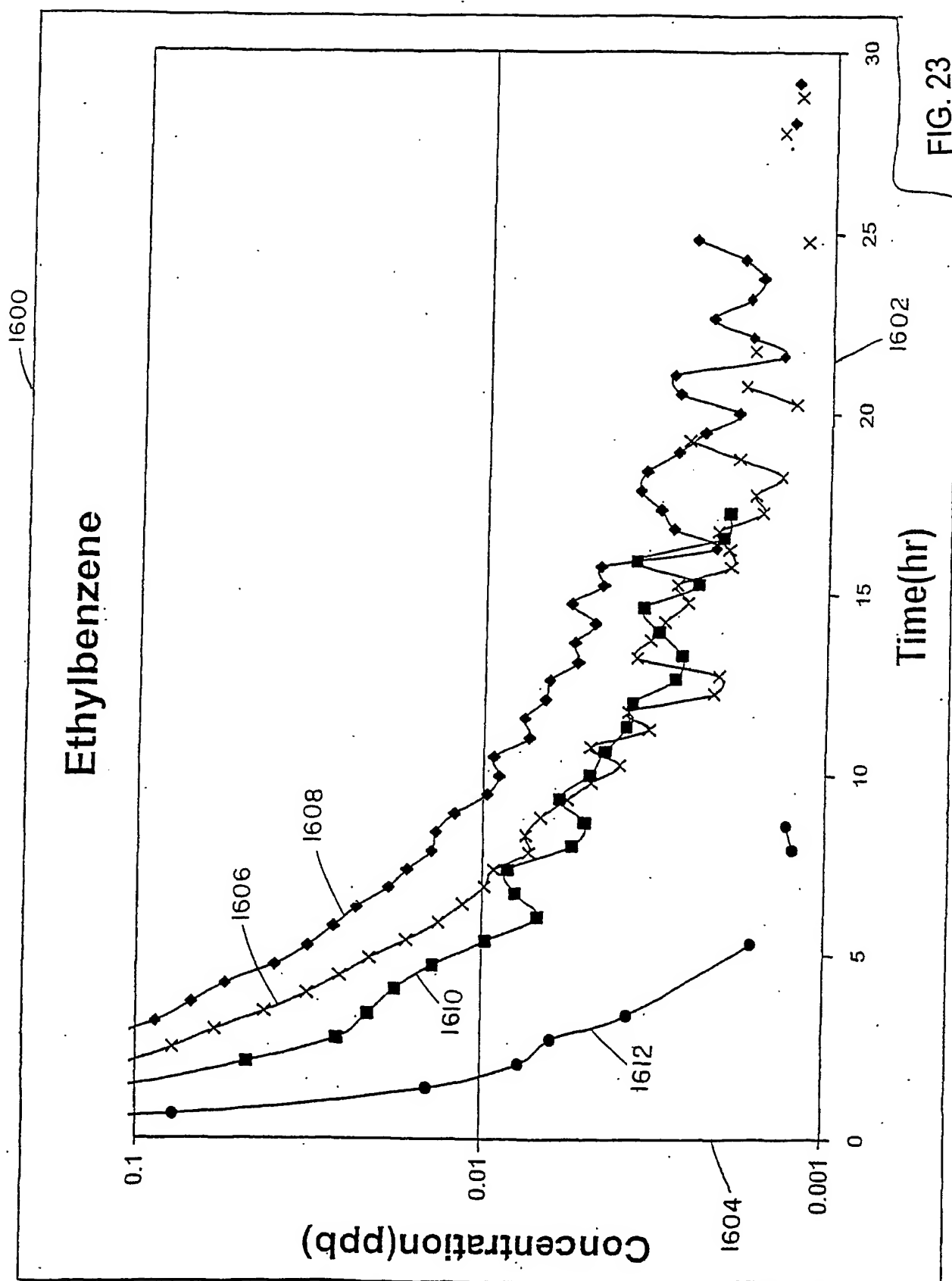
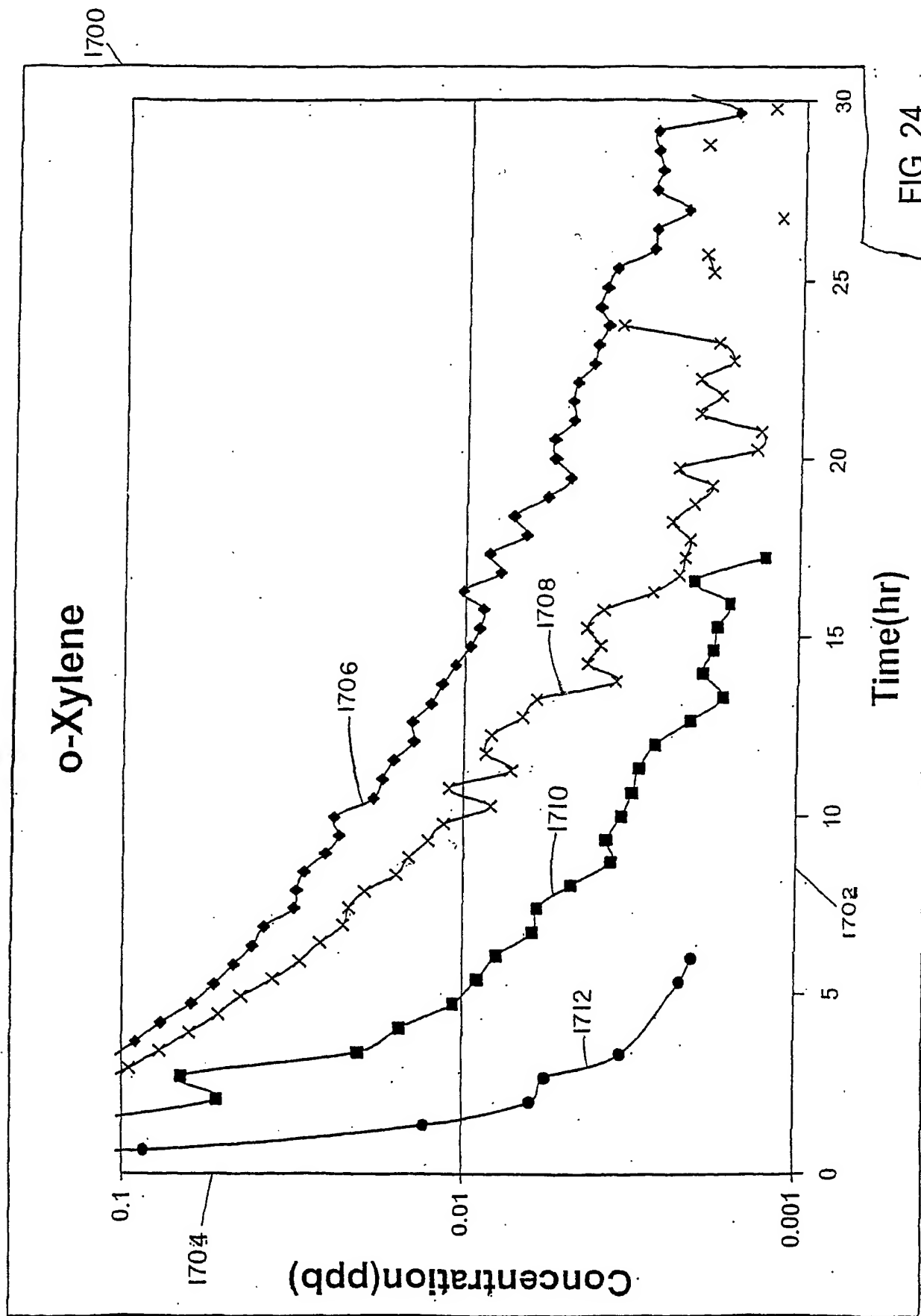


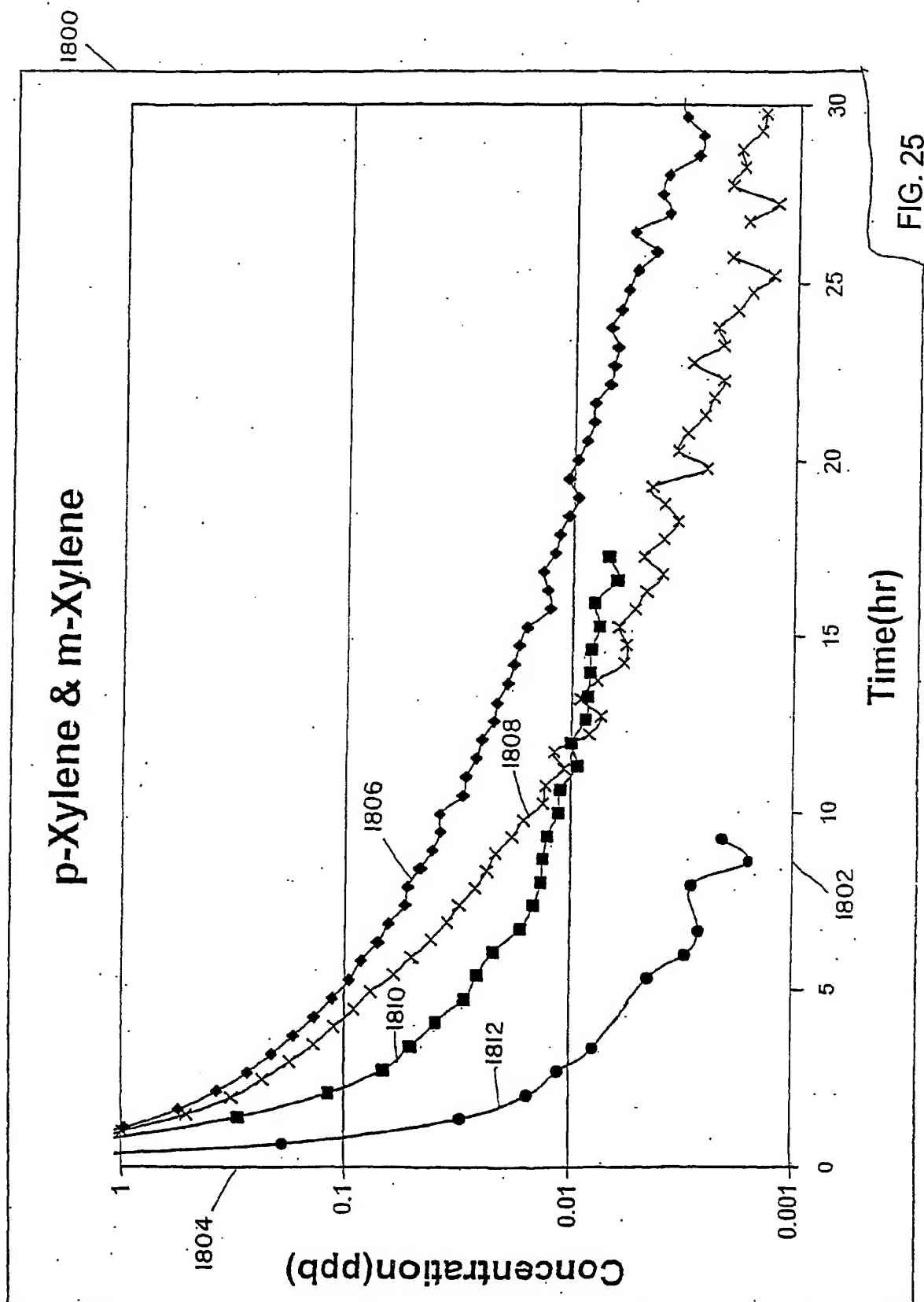
FIG. 22

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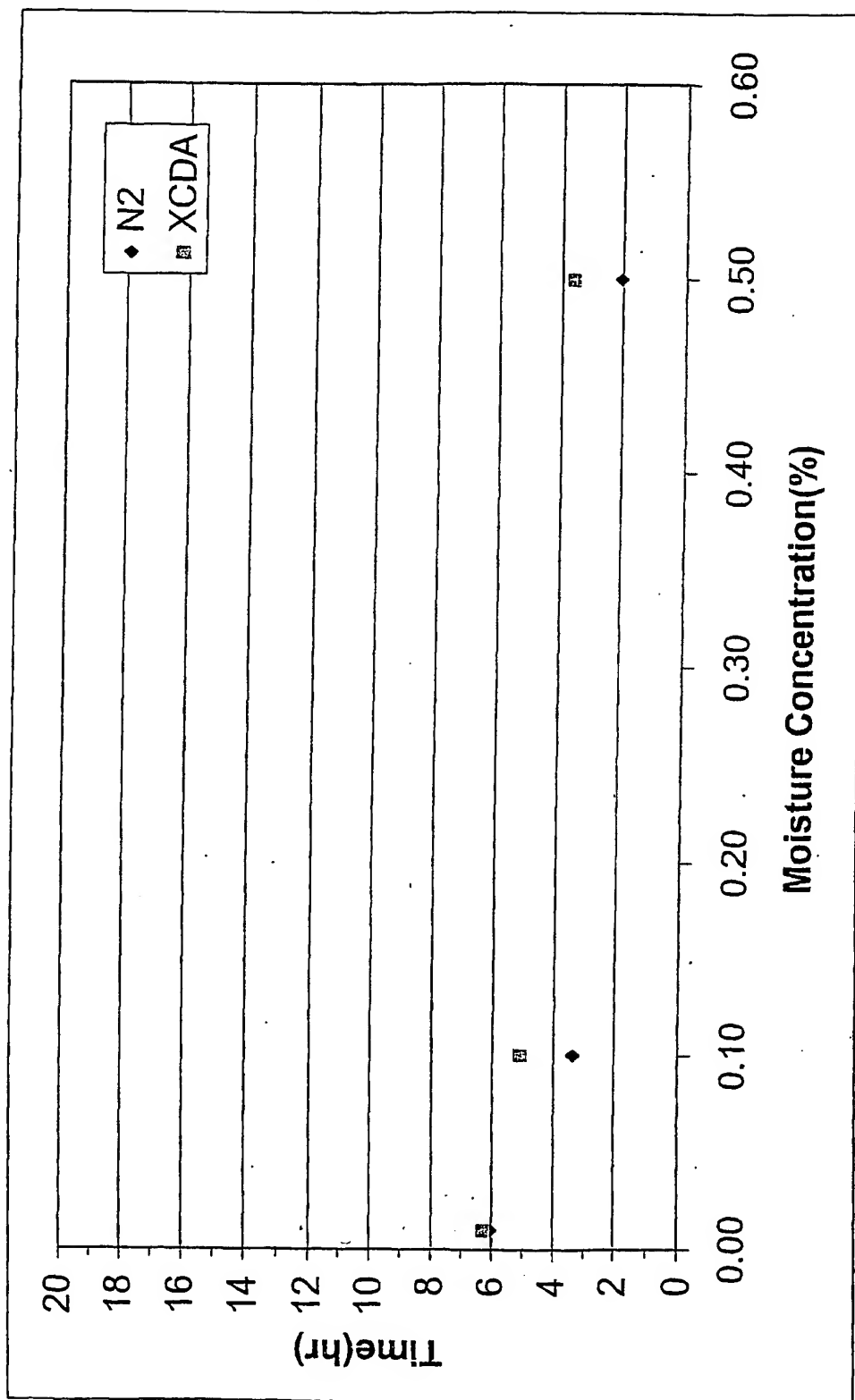


FIG. 26

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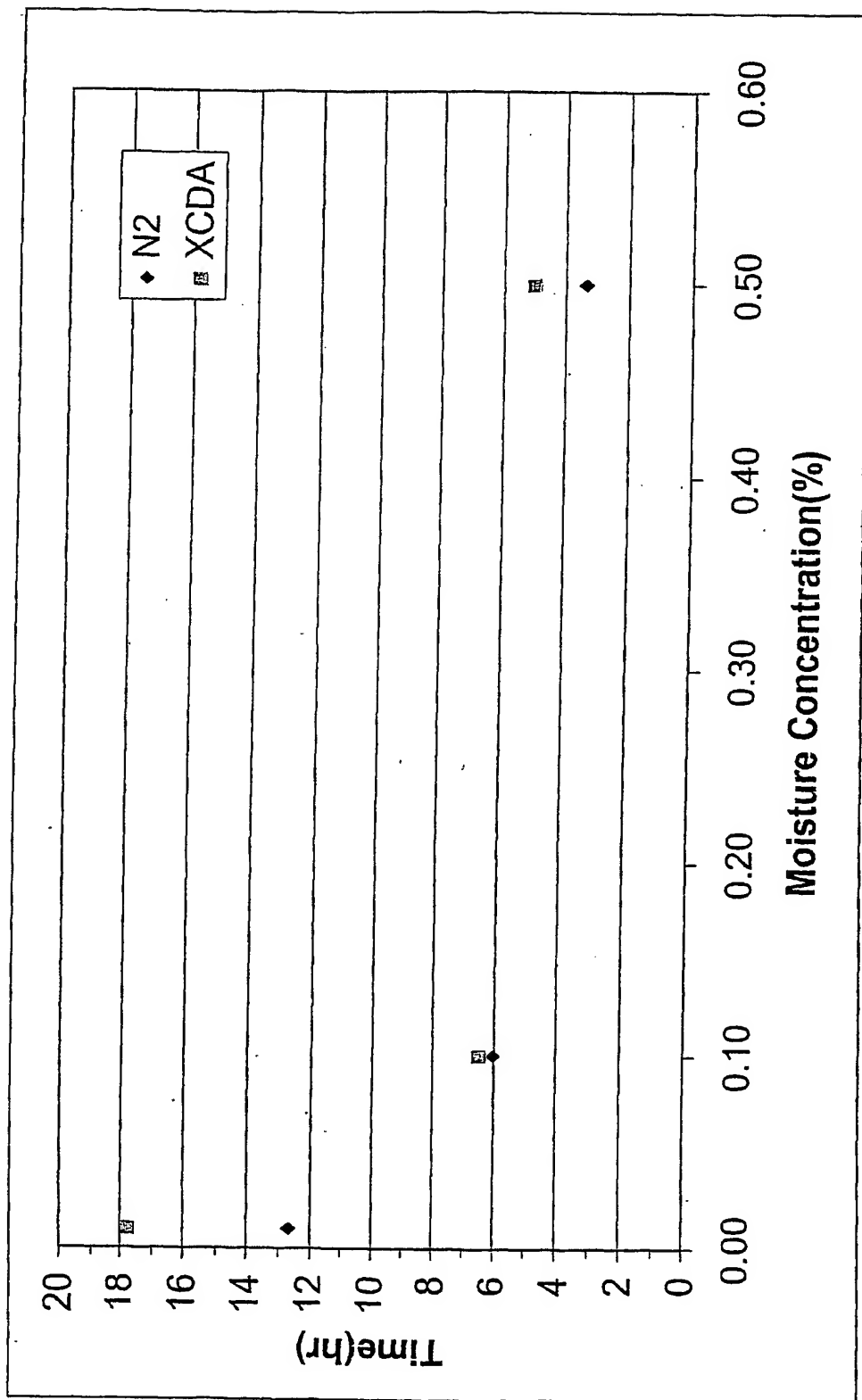


FIG. 27

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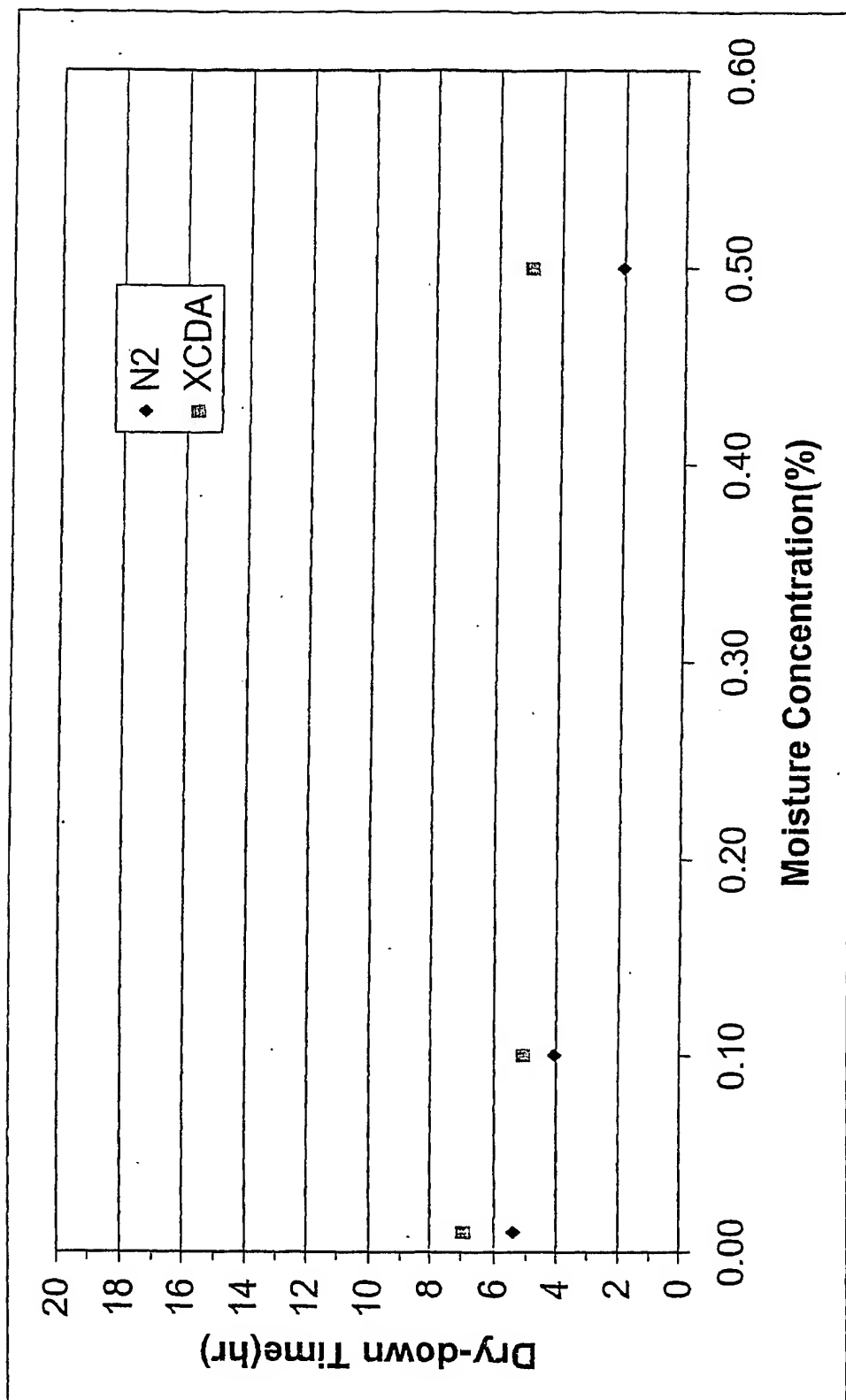


FIG. 28

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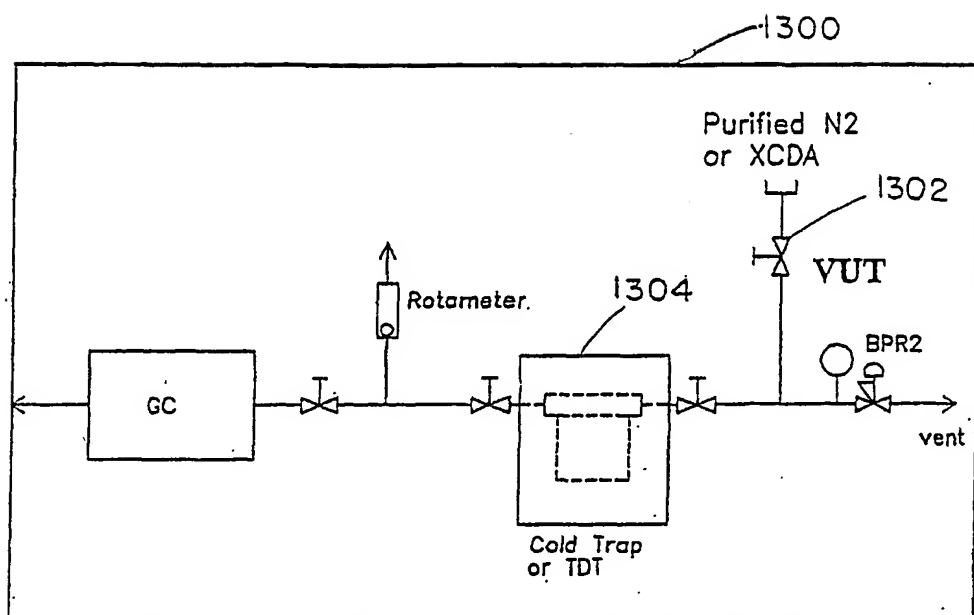


FIG. 29

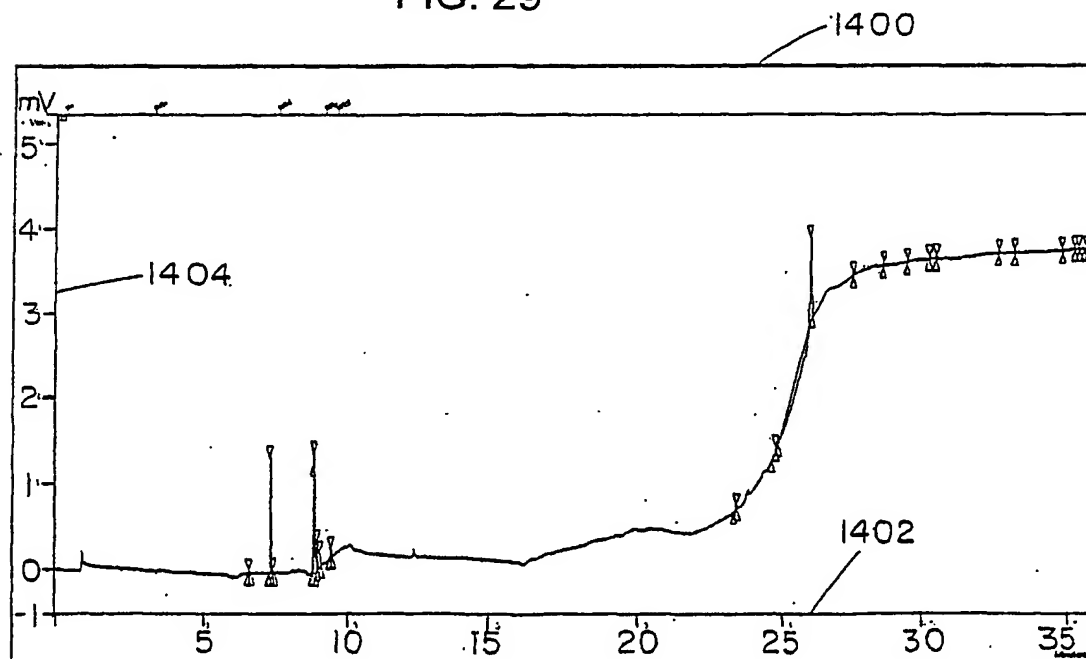


FIG. 30

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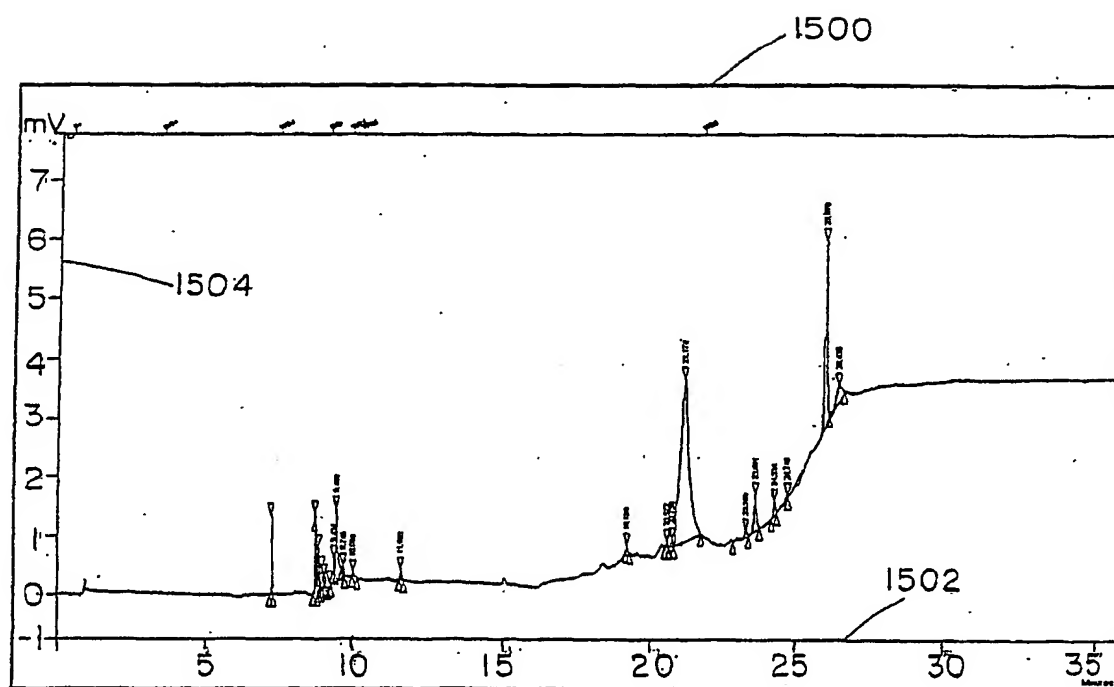


FIG. 31